

AISP NSR-2205i11D Lens Data Sheet

Serial Number of NSR: User's Machine ID: Software :

Acceptance Test Completion Date:

Worked by:

Accepted by:

No	Item	Specification	Result			
1	Exposure Power		744mW/cm ²			
2	Illumination Uniformity		0.83%			
3	Stepping Accuracy		X	20nm	Y	22nm
4	Back Stepping Accuracy		X	27nm	Y	17nm
5	Lens Distortion (Including Magnification error) "JUST Confirm" Item		Max			
			X	33nm	Y	30nm
			Min			
			X	-41nm	Y	-35nm
6	Inclination		UR - LL		2nm	
			UL - LR		96nm	
7	Overlay-LSA		X	41nm	Y	33nm
8	Overlay-FIA	Average Data High, 3 Sigma Data Good	X	81nm	Y	99nm

Lamp Uniformity

2025/11(AD36003)

Process Program :
Comment :
Relic :

Lamp Illumination Uniformity

Condition File: 22LAMP.LMCP
Result File: LAMP-20250512.LAMP
Machine ID: AD36003
Date: 2025-05-12 12:23:55
Comment: LAMP Illumination Uniformity (11*13)

Measurement Condition		Measurement Result Summary	
Illumination ID :	1	Maximum :	752.148 [mW/cm ²]
Intra-field Repeat Count :	3	Minimum :	739.842 [mW/cm ²]
Map Layout		Average :	744.887 [mW/cm ²]
X :	11	Uniformity :	0.825 [%]
Y :	13		
Diameter :	31.11 [mm]		
Measurement Limits			
-X :	-11000.00 [μm]		
+X :	11000.00 [μm]		
-Y :	-12700.00 [μm]		
+Y :	12500.00 [μm]		
Power Trans. Rate :	1.00		
Sensor Position			
X :	130206.50 [μm]		
Y :	77860.00 [μm]		
Average Number :	1		
Step Mode :	Normal		
Dummy Shot			
Blind Setting :	Pinhole		
Frequency :	10		
Time :	100 [msec]		
Wait Time :	100 [msec]		

Search :

Initialize or Reset

PROCE

CALIBRA machine

F6 Param.

F10 Map

F14 Exit

PAUSE

RESUME

STOP

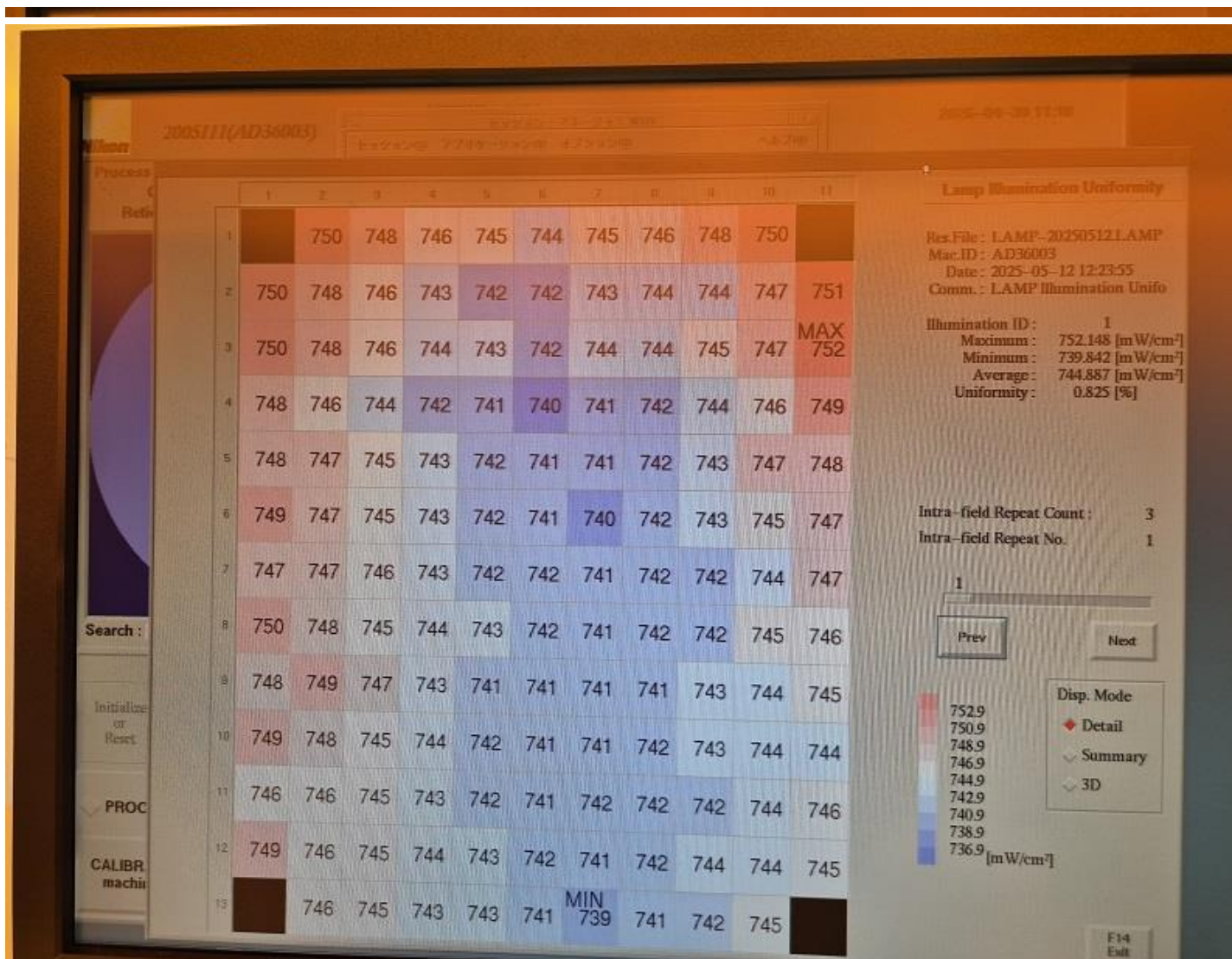
HELP

IZEコマンド開始
了
Eコマンド開始

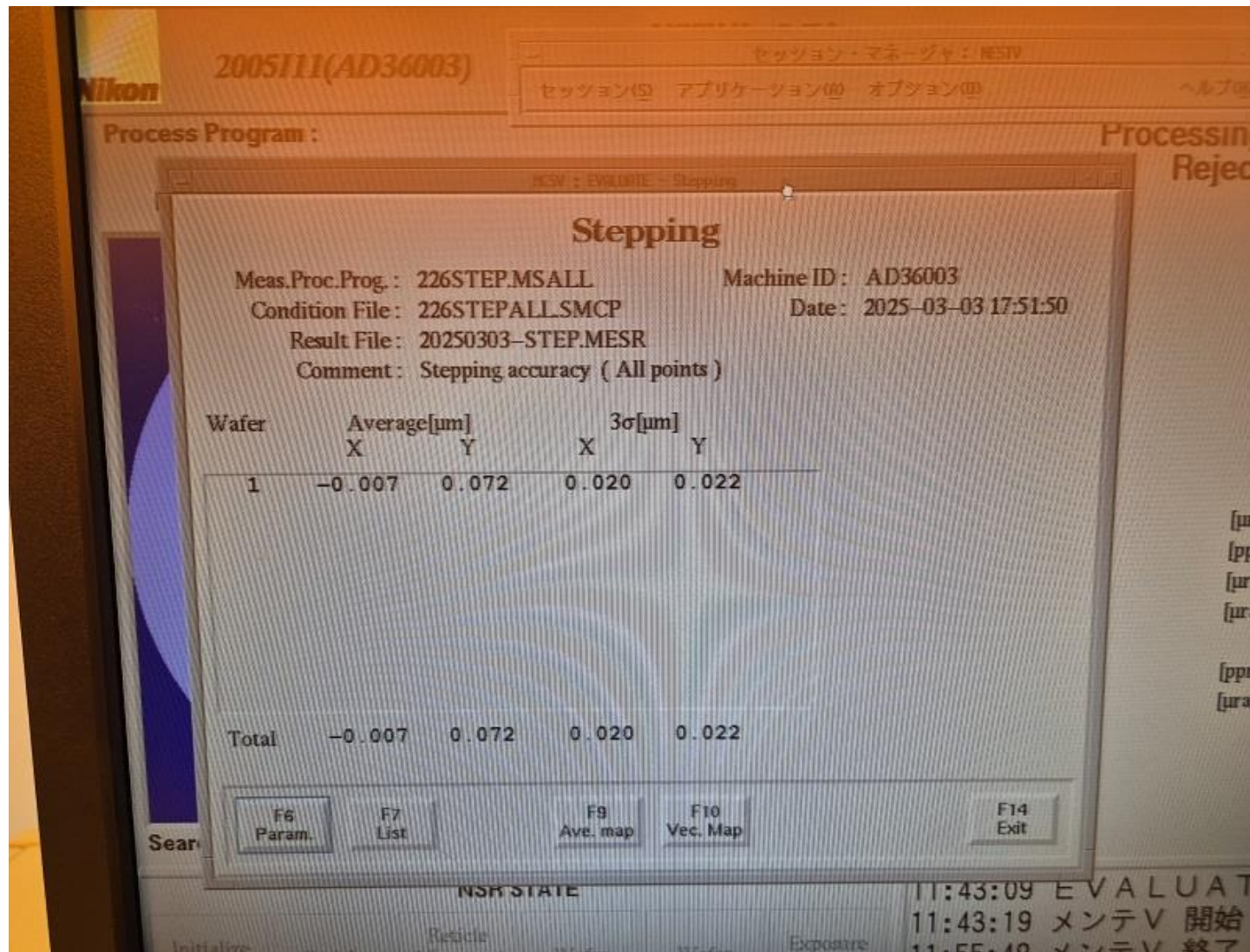
COMMUNICATE

OPERATOR

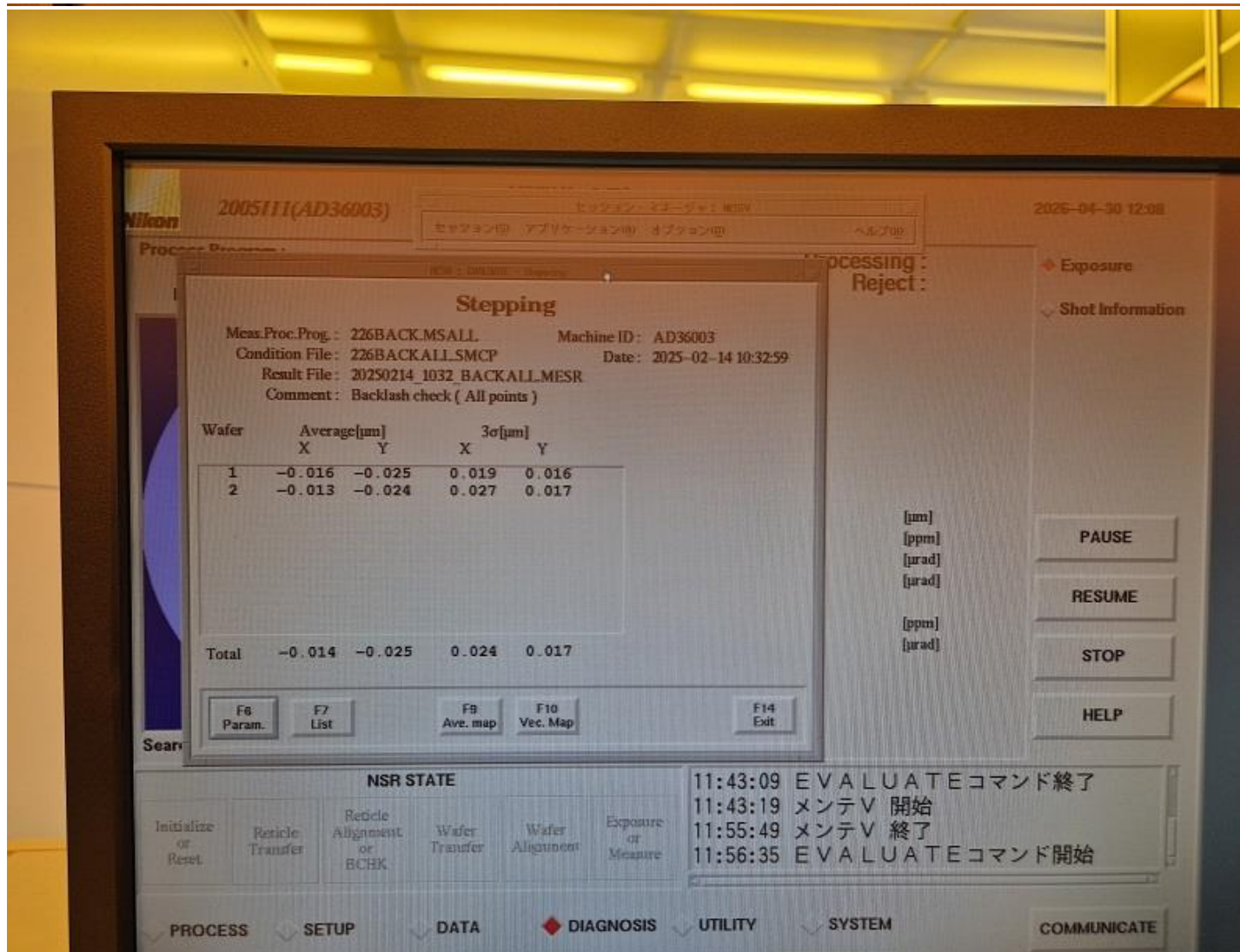
Lamp Uniformity



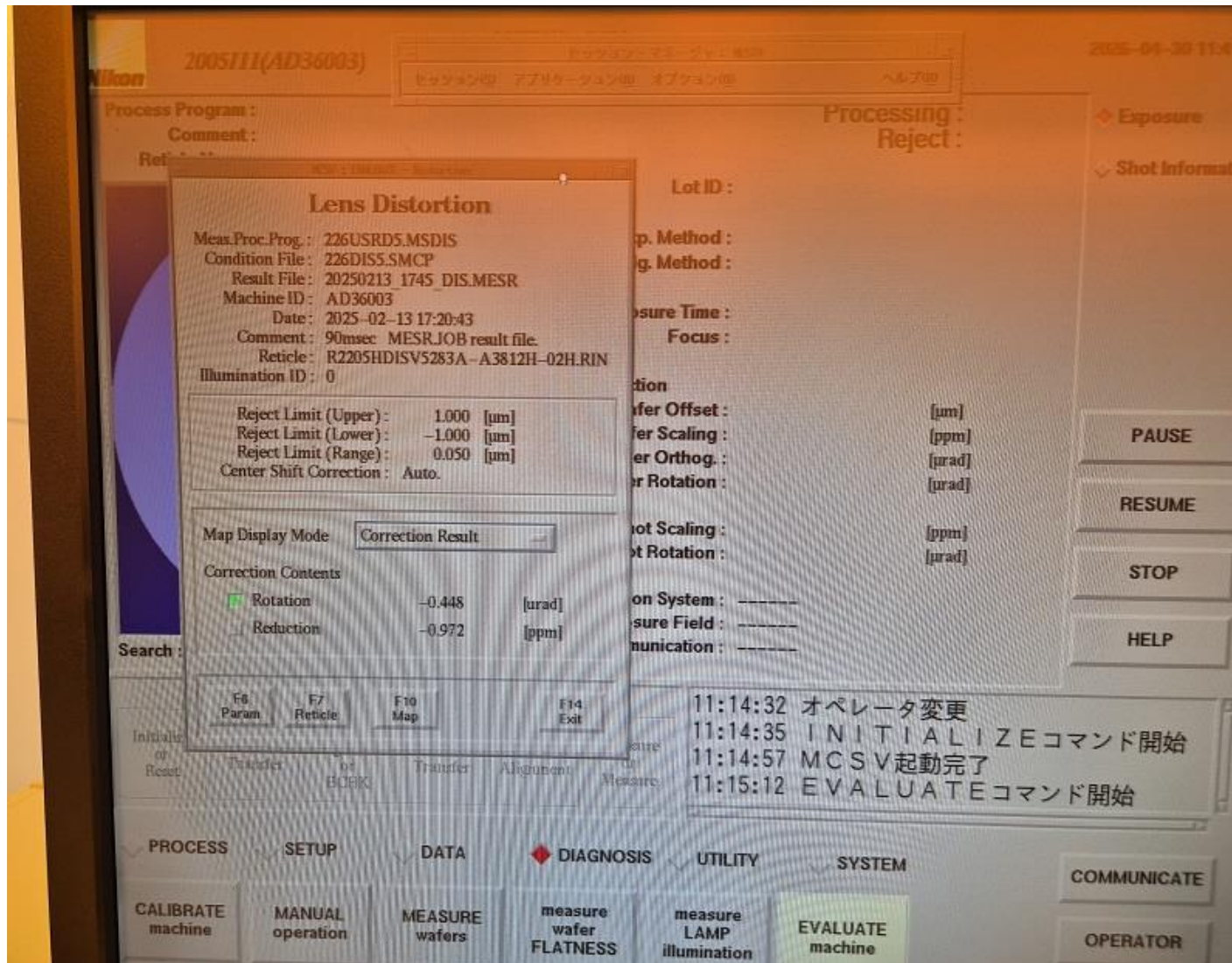
Stepping Accuracy



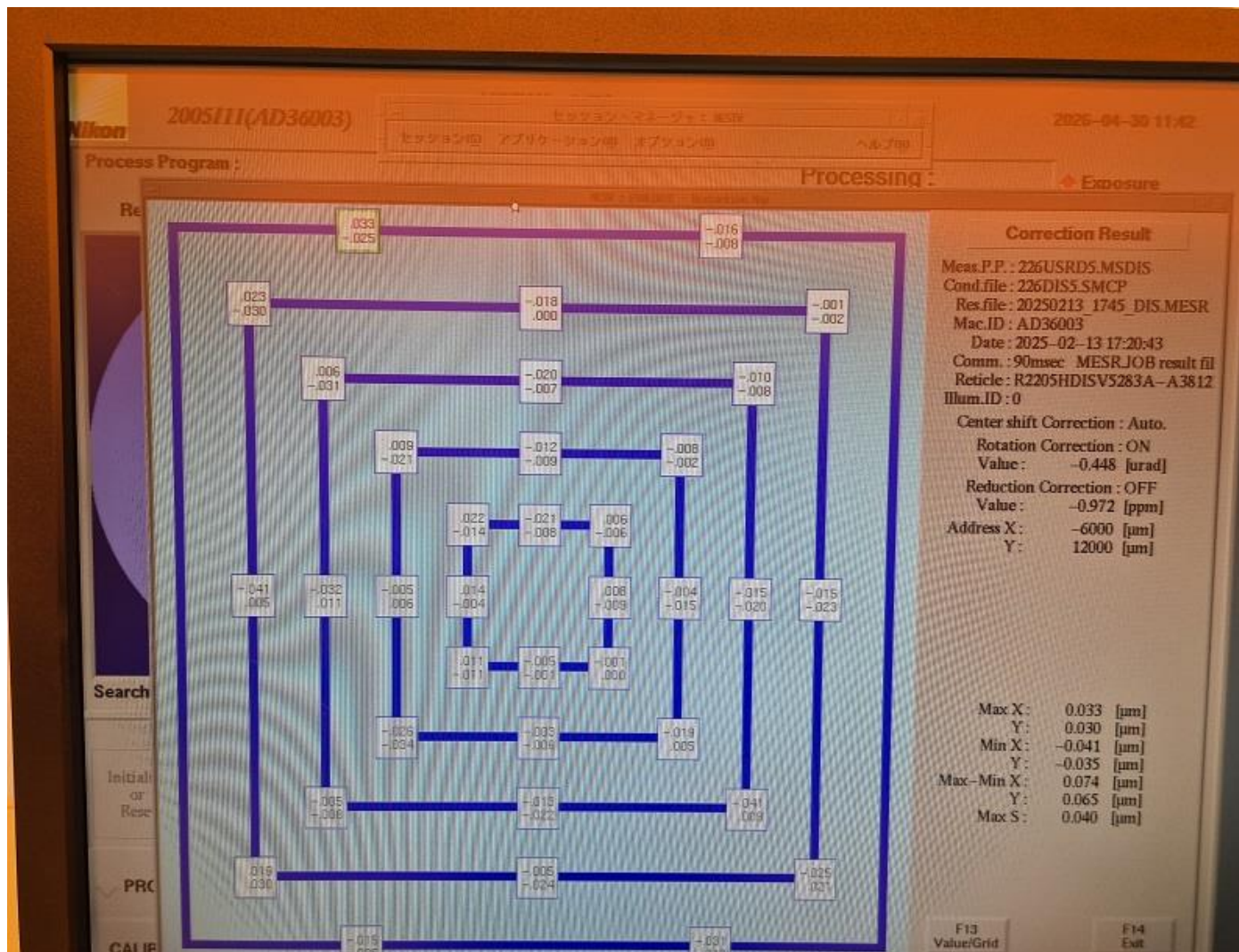
Stepping Accuracy



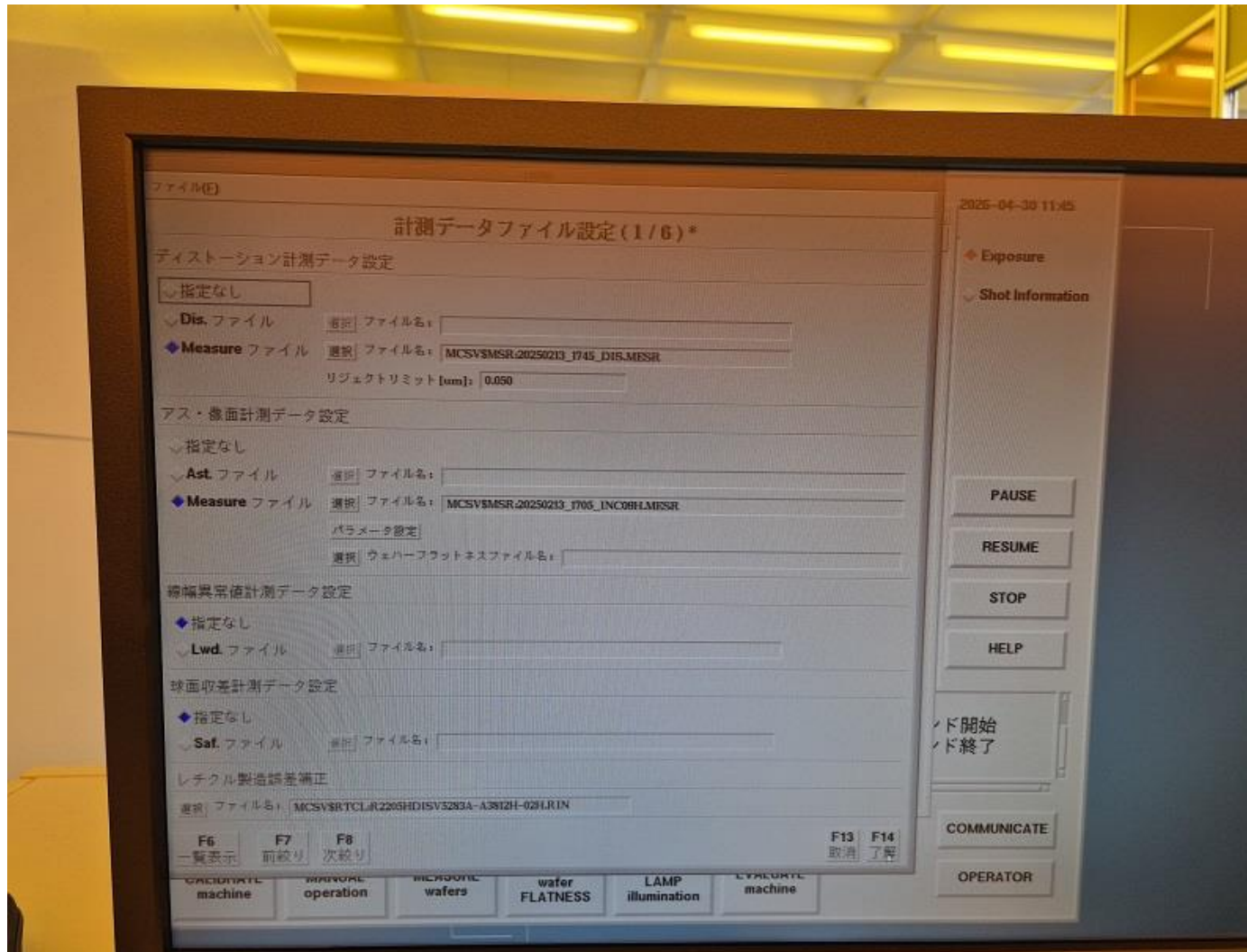
Lens Distortion



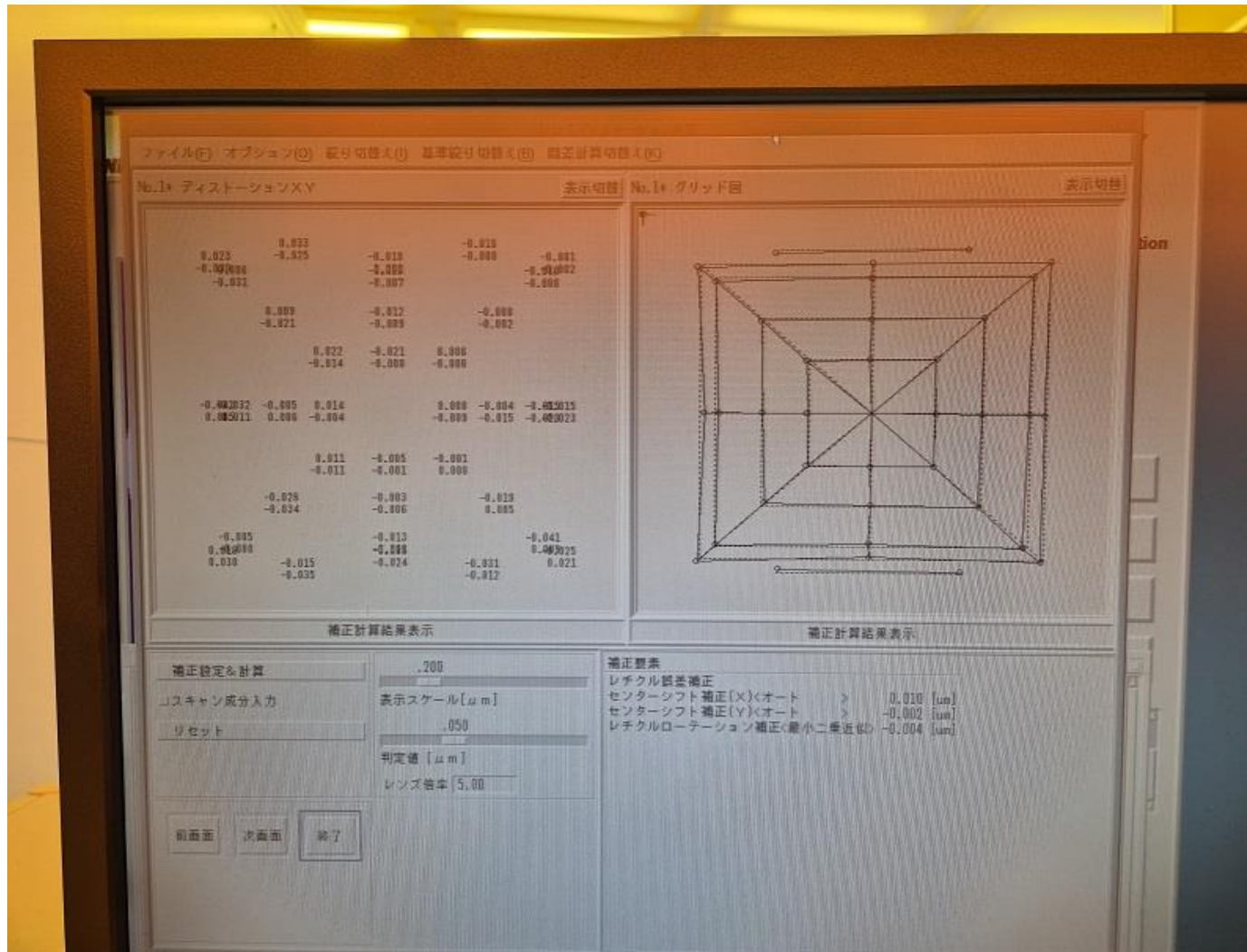
Lens Distortion



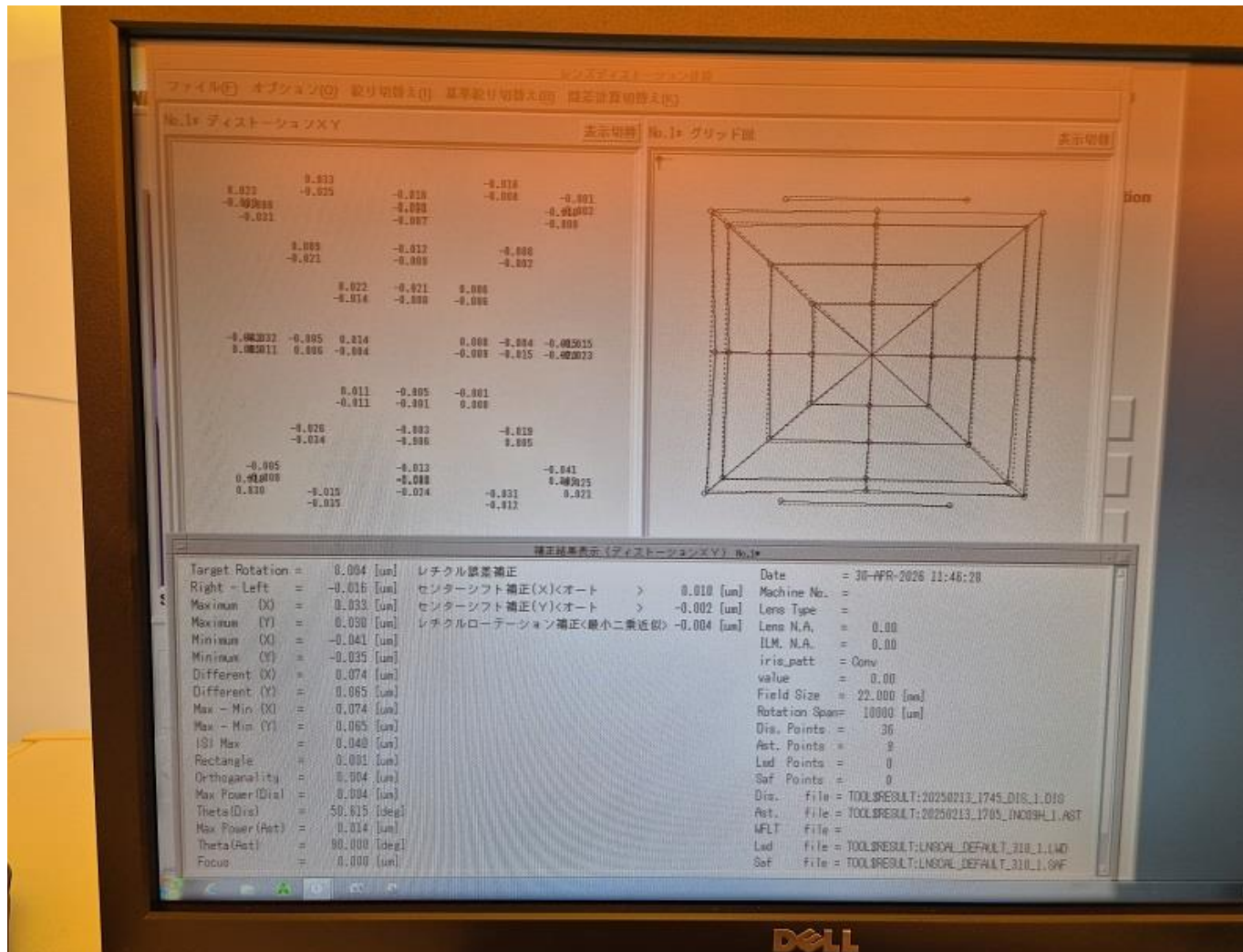
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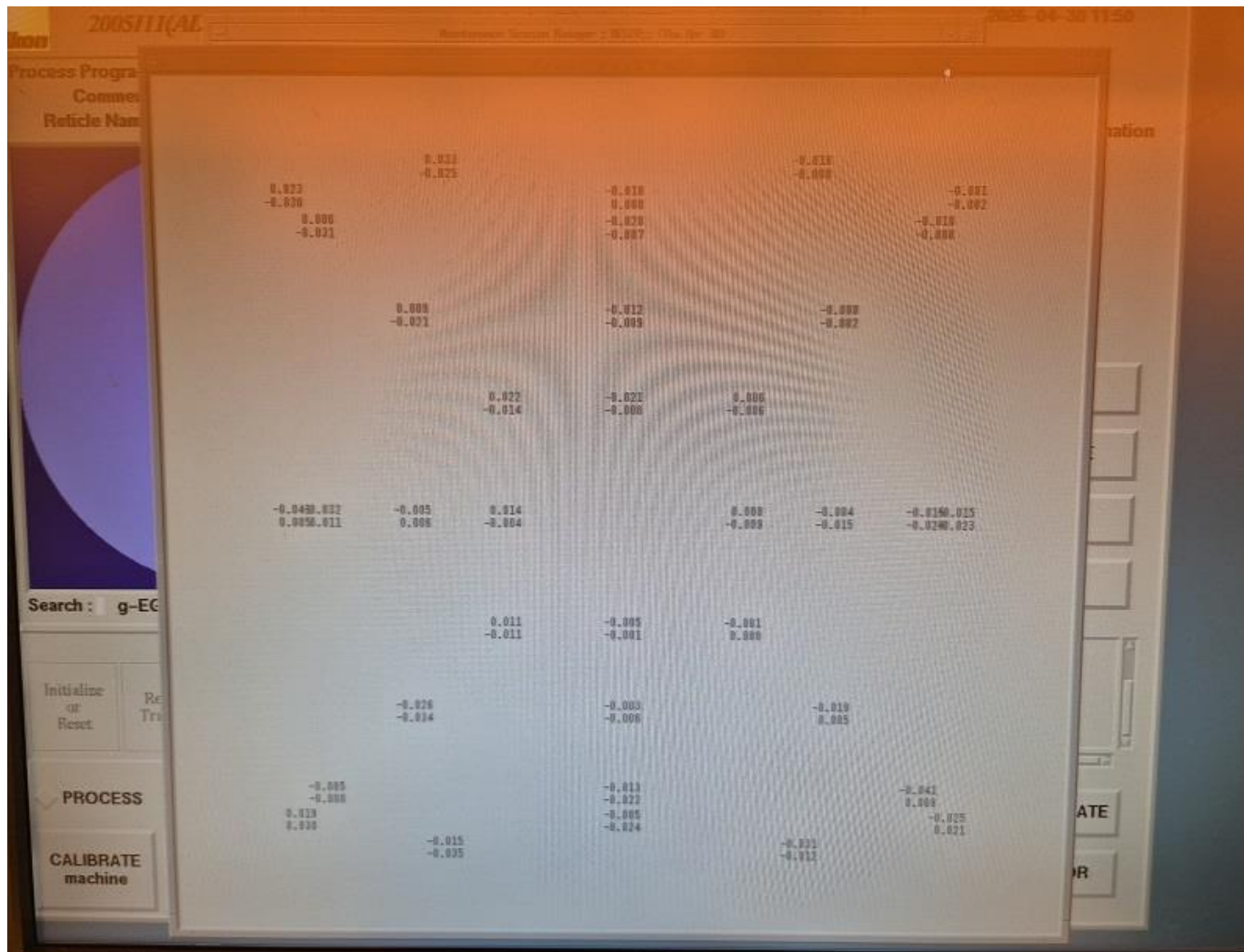
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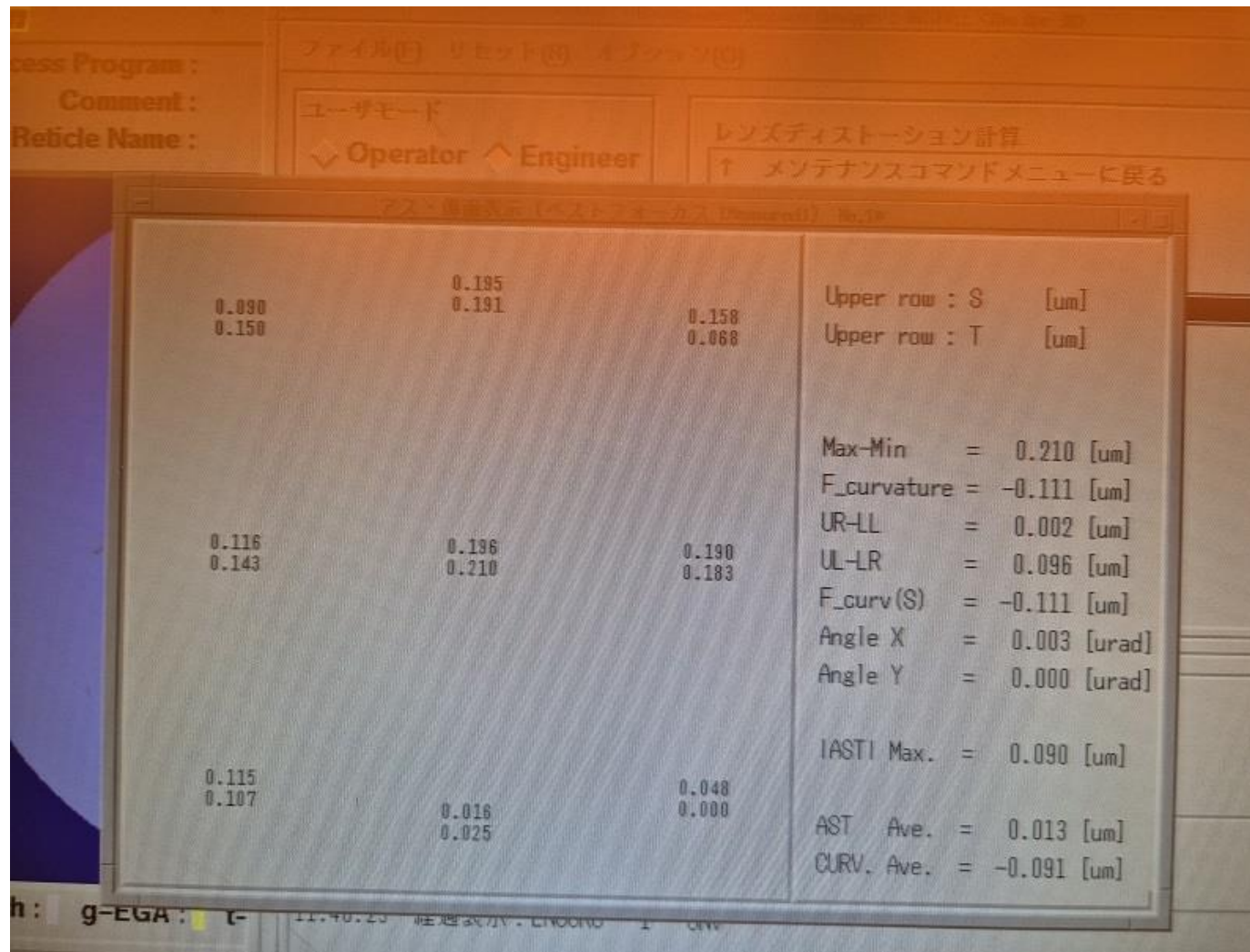
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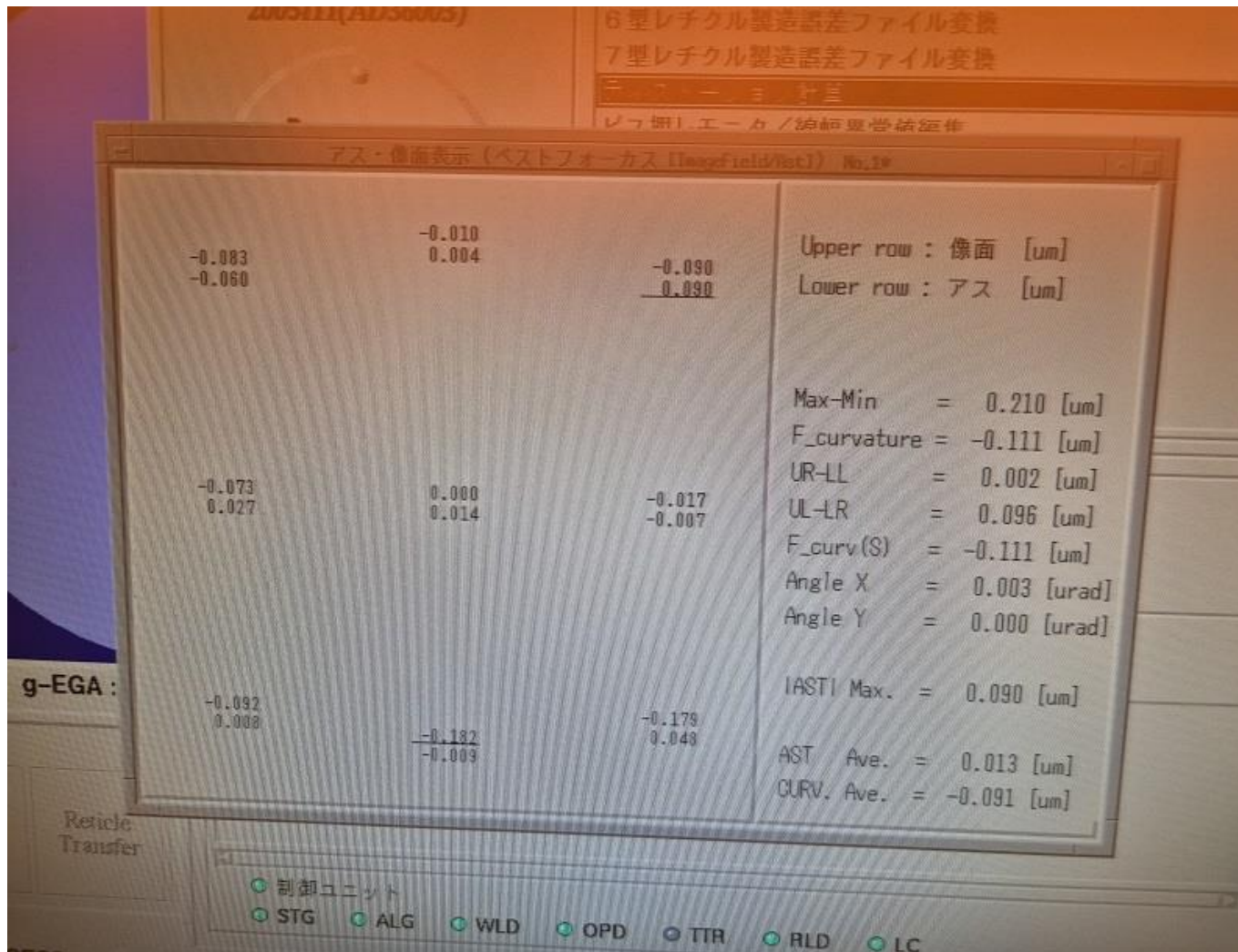
Lens Distortion



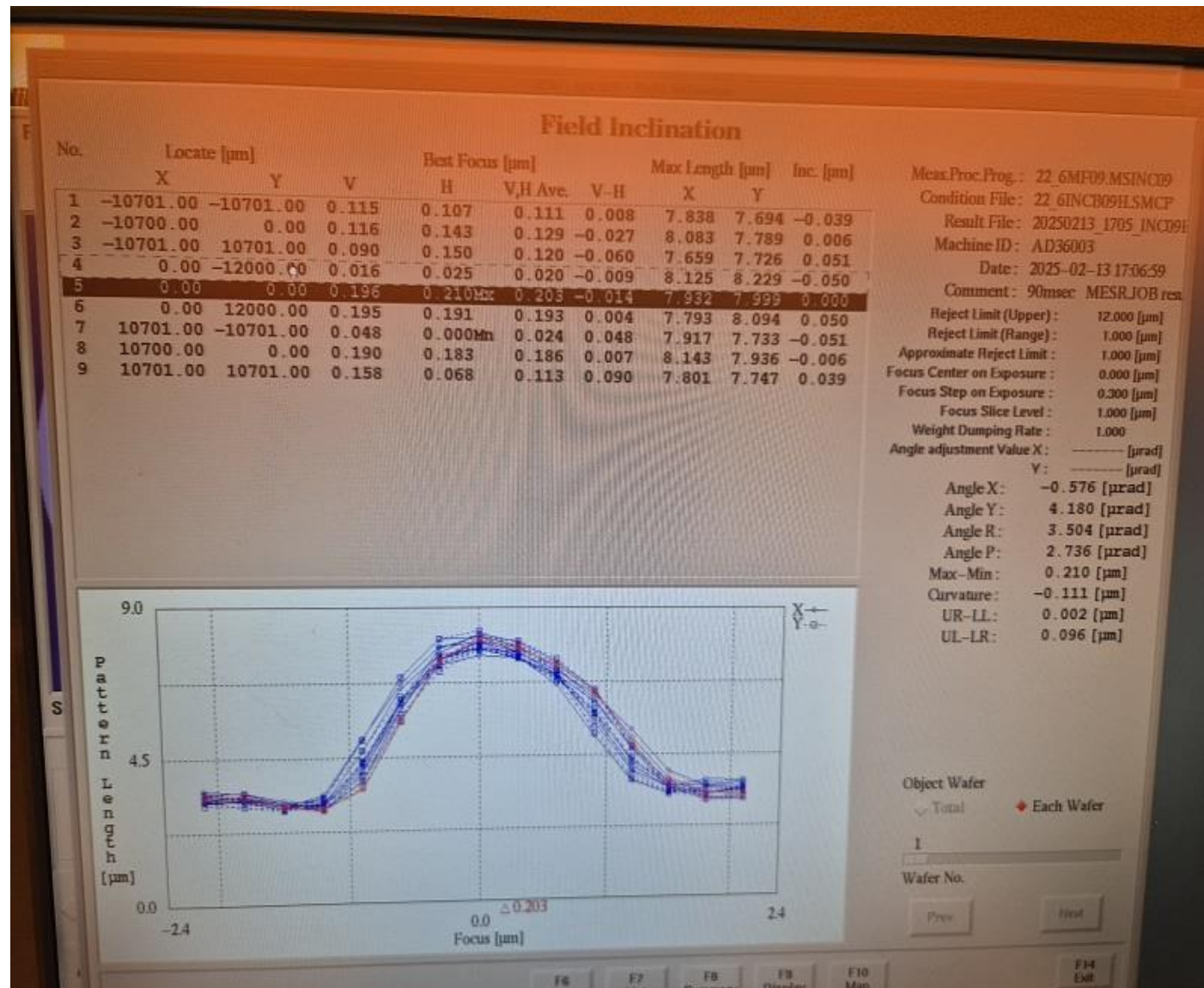
Lens Distortion



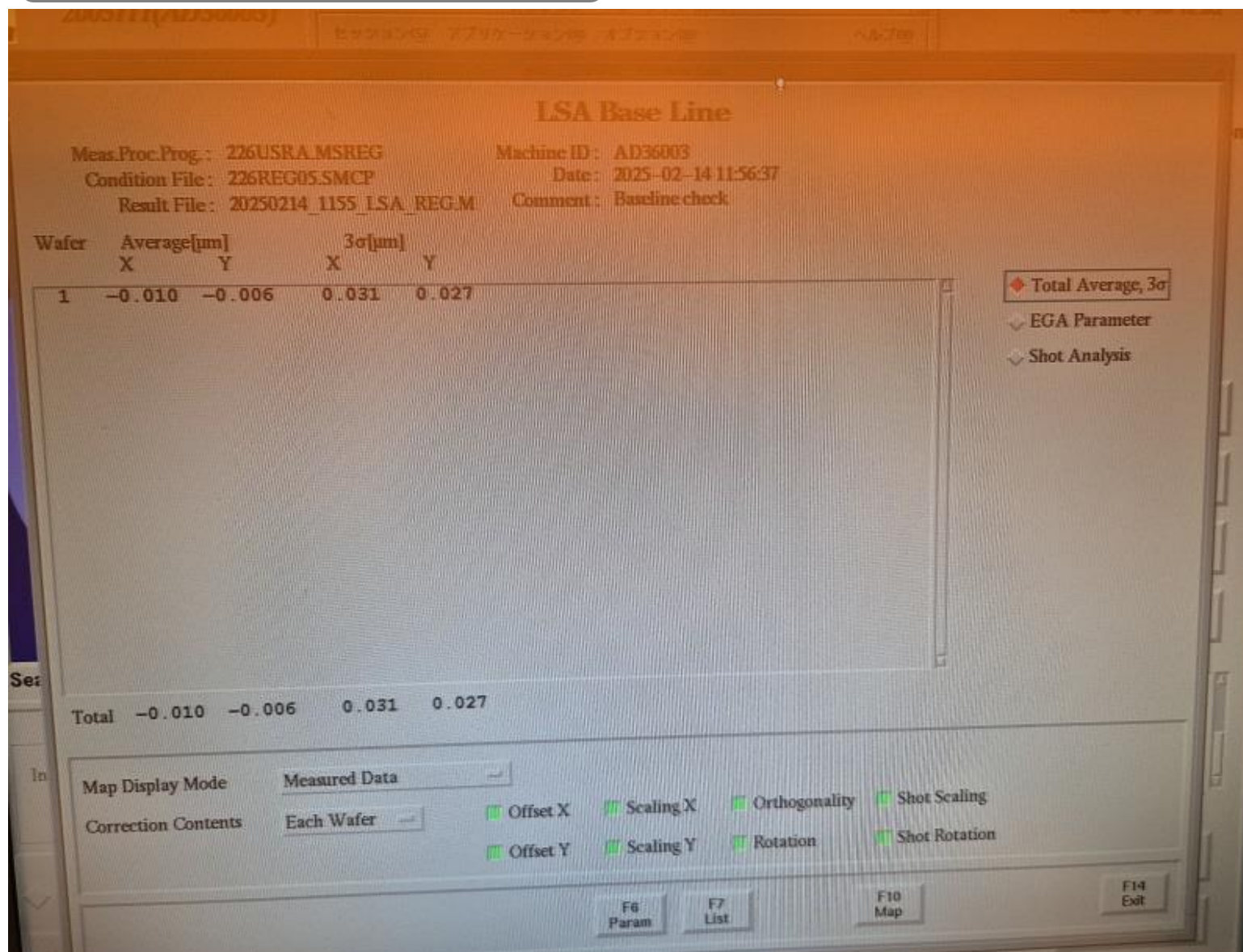
Lens Distortion



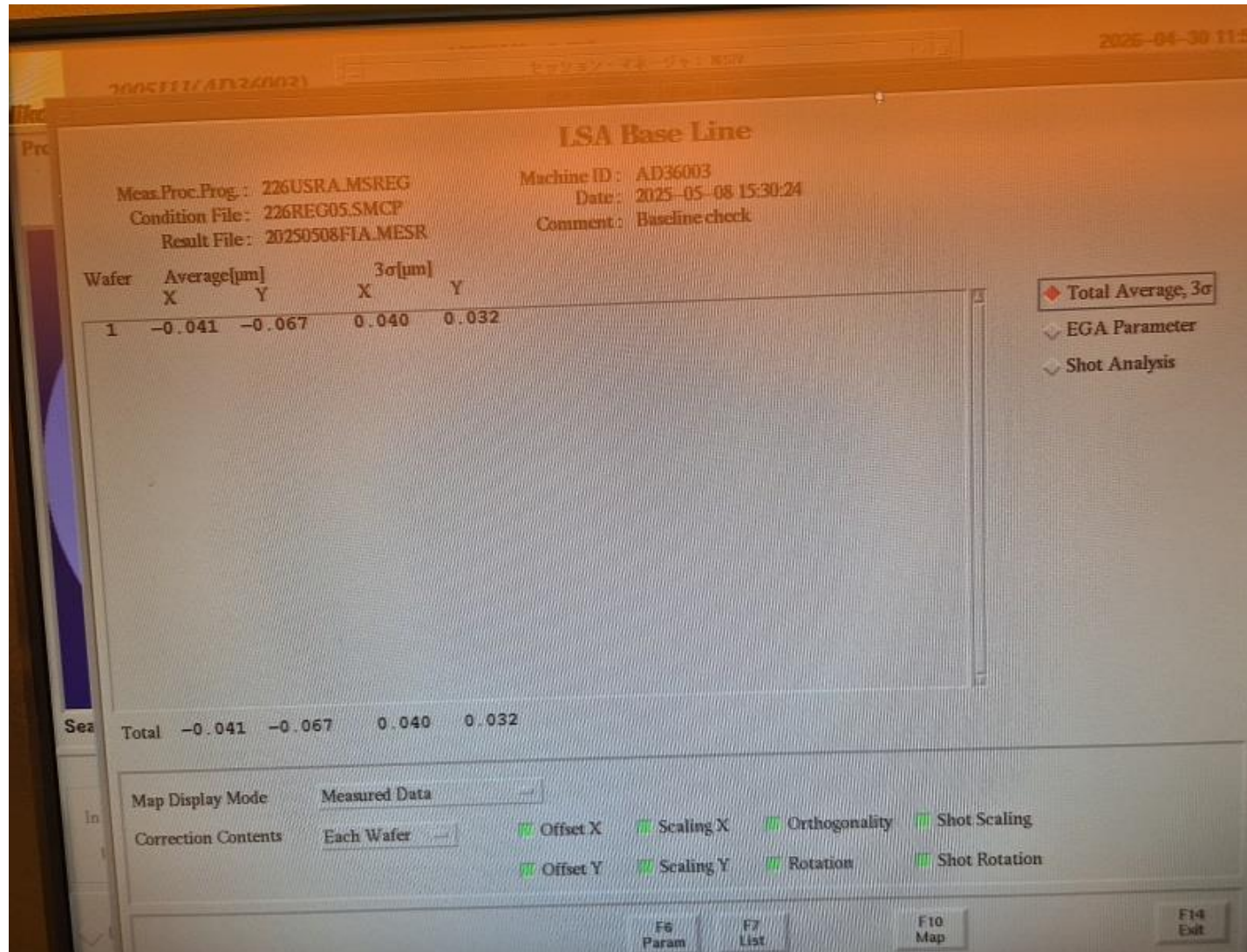
Inclination



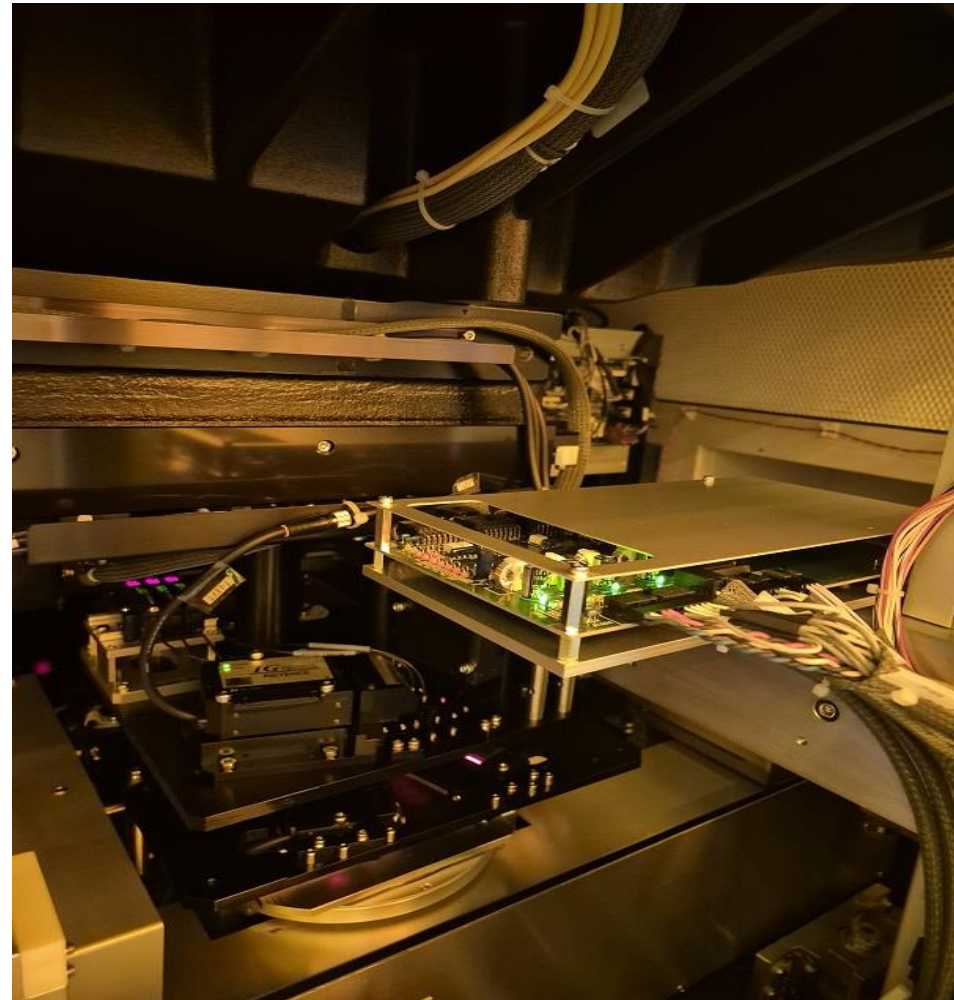
LSA Overlay Accuracy



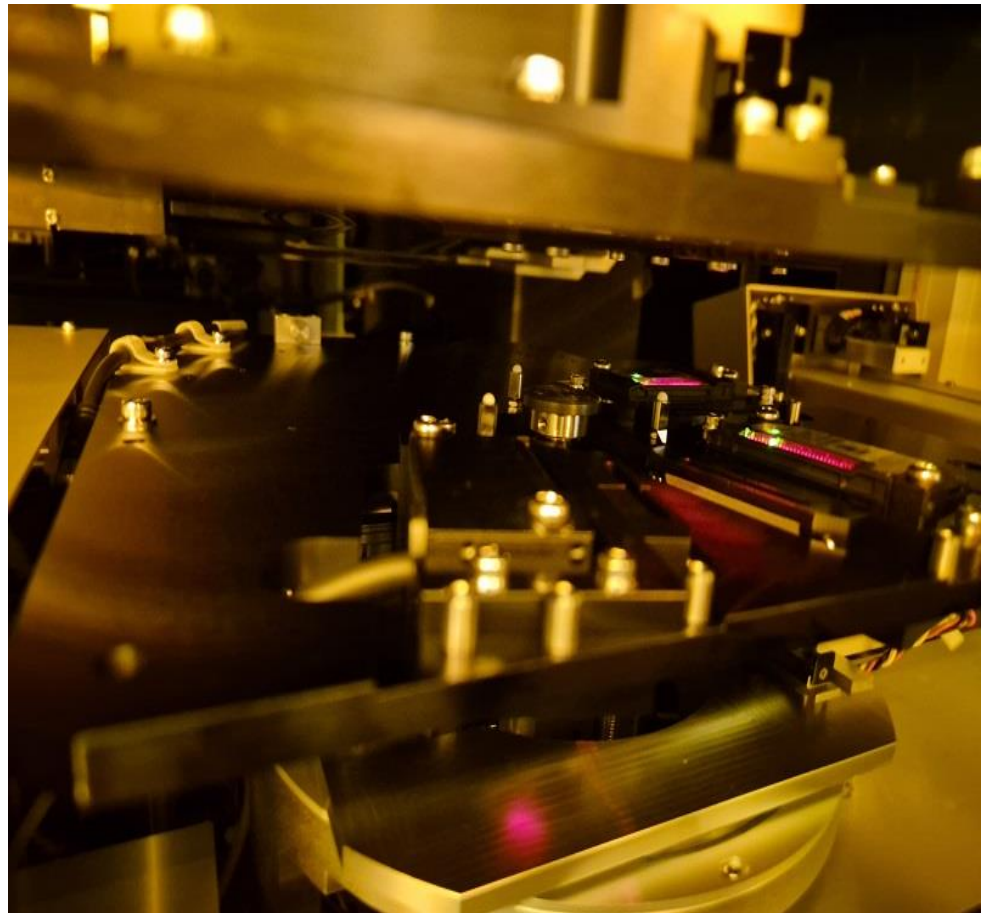
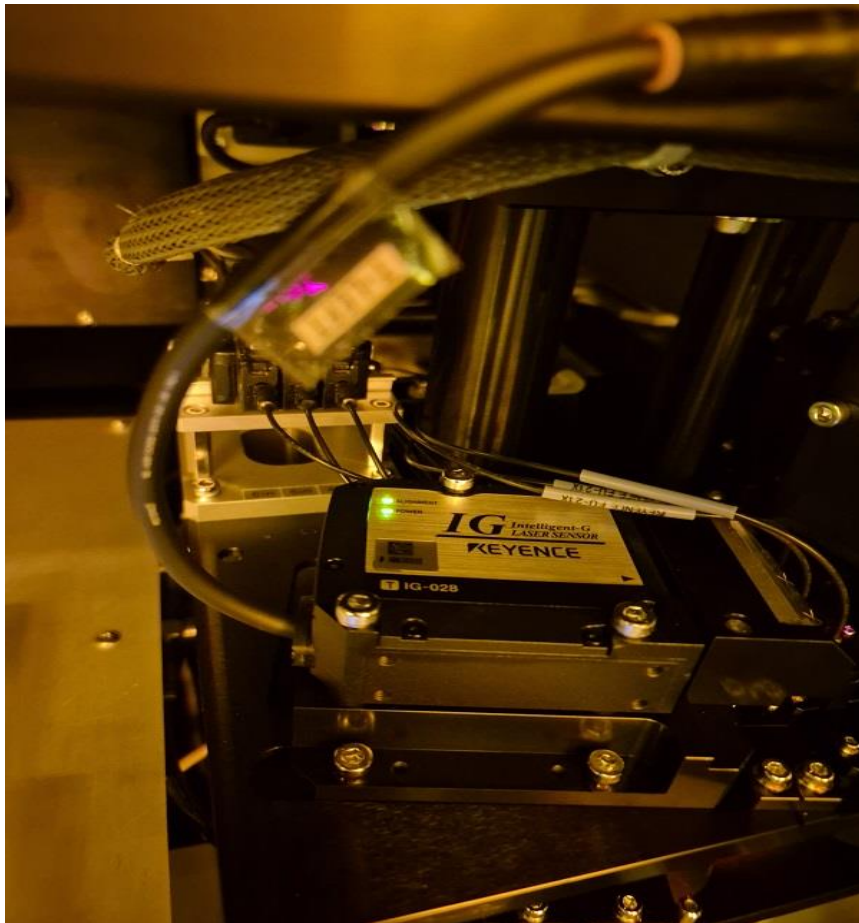
FIA Overlay Accuracy



Wafer Loader OF



Wafer Loader OF



Wafer Loader OF

